

Tien Hsi Lee

List of Publications by Year in descending order

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papers

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citing authors

#	ARTICLE	IF	CITATIONS
1	Low-temperature rough-surface wafer bonding with aluminum nitride ceramics implemented by capillary and oxidation actions. <i>Ceramics International</i> , 2022, 48, 8766-8772.	4.8	1
2	Low-Temperature Rough-Surface Wafer Bonding with AlN/AlN Via Oxygen Plasma Activation. <i>ECS Transactions</i> , 2022, 108, 49-50.	0.5	0
3	Low-Temperature Rough-Surface Wafer Bonding with AlN/AlN Via Oxygen Plasma Activation. <i>ECS Meeting Abstracts</i> , 2022, MA2022-01, 1046-1046.	0.0	0
4	Utilization of Low Wavelength Laser Linking with Electrochemical Etching to Produce Nano-Scale Porous Layer on p-Type Silicon Wafer with High Luminous Flux. <i>ECS Journal of Solid State Science and Technology</i> , 2021, 10, 016003.	1.8	0
5	Self-Powered, Hybrid, Multifunctional Sensor for a Human Biomechanical Monitoring Device. <i>Applied Sciences (Switzerland)</i> , 2021, 11, 519.	2.5	5
6	Forming a Photoluminescent Layer on Another Surface in the Dark through Lasering of N-Type Silicon in an Electrolyte. <i>ACS Omega</i> , 2020, 5, 26497-26503.	3.5	3
7	Annihilating Pores in the Desired Layer of a Porous Silicon Bilayer with Different Porosities for Layer Transfer. <i>Scientific Reports</i> , 2019, 9, 12631.	3.3	12
8	Communicationâ€™Effect of Free-Carrier Absorption on an Anodized Silicon Surface for Producing Dense and Uniform Nanocrystals. <i>Journal of the Electrochemical Society</i> , 2018, 165, H99-H101.	2.9	2
9	Rapid Fabrication of 100 nm or Thinner Fully Depleted Silicon-on-Insulator Materials for Ultralow Energy Consumption. <i>ACS Applied Nano Materials</i> , 2018, 1, 2414-2420.	5.0	2
10	Near-Field Electrospun Piezoelectric Fibers as Sound-Sensing Elements. <i>Polymers</i> , 2018, 10, 692.	4.5	28
11	Communicationâ€™Eliminating Thickness Measurement Uncertainty of Capacitive Displacement Sensor in High Resistivity Substrate by Photoconduction. <i>ECS Journal of Solid State Science and Technology</i> , 2017, 6, P323-P325.	1.8	0
12	Nanoscale Layer Transfer by Hydrogen Ion-Cut Processing: A Brief Review Through Recent U.S. Patents. <i>Recent Patents on Nanotechnology</i> , 2017, 11, 42-49.	1.3	3
13	Inhibition Effect of a Laser on Thickness Increase of p-Type Porous Silicon in Electrochemical Anodizing. <i>Journal of the Electrochemical Society</i> , 2016, 163, H265-H268.	2.9	11
14	Sharpening Si Nanocrystals on the Bulk Surface by Nanoscale Electrochemistry through Controlling the Hole Current with the Irradiation of Near-Infrared Laser. <i>Journal of the Electrochemical Society</i> , 2016, 163, E258-E262.	2.9	3
15	Thermal Stress Induced Thin Film Transfer from Single-crystal Silicon Layer on Sapphire Substrate. <i>Integrated Ferroelectrics</i> , 2013, 144, 73-78.	0.7	0